

Electronic Patent Application Fee Transmittal

Application Number:	09546174			
Filing Date:	11-Apr-2000			
Title of Invention:	HIGH DENSITY PLASMA CHEMICAL VAPOR DEPOSITION PROCESS			
First Named Inventor/Applicant Name:	Chih-Chien Liu			
Filer:	William H. Wright/Lillian Rodriguez			
Attorney Docket Number:	JIA 462C1			
Filed as Large Entity				
Utility Filing Fees				
Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Basic Filing:				
Pages:				
Claims:				
Miscellaneous-Filing:				
Petition:				
Patent-Appeals-and-Interference:				
Notice of appeal	1401	1	510	510
Post-Allowance-and-Post-Issuance:				
Extension-of-Time:				

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Miscellaneous:				
Total in USD (\$)				510